FORM PTO-1449 (Modified)	SEP 0 7	7.1	ATTY. DOCKET NO. YOR920000692US1	SERIAL NO. 09/769,170		
LIST OF PATENTS AND PUBLICATIONS OF FOR APPLICANT'S INFORMATION DISCLOSURE STATEMENT			APPLICANT: J.O. Chu et al.			
(Use several sheets if necessary)			FILING DATE: January 25, 2001	GROUP: 2811		

REFERENCE DESIGNATION U.S

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EXAMINER

SI

DATE CONSIDERED /2-10-02

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.